

	L #	Hits	Search Text	DBs	Time Stamp
1	L1	276	(427/539).CCLS.	USPAT; US-PGP UB; EPO; JPO; DERWEN T; IBM_TD B	2002/03/21 13:29
2	L2	129187	tantalum Ta Titanium Ti zirconium Zr barium Ba strontium Sr)adj(oxide dioxide pentoxide	USPAT; US-PGP UB; EPO; JPO; DERWEN T; IBM_TD B	2002/03/21 13:34
3	L3	223799	tantalum Ta Titanium Ti zirconium Zr barium Ba strontium Sr)with(oxide dioxide pentoxide	USPAT; US-PGP UB; EPO; JPO; DERWEN T; IBM_TD B	2002/03/21 13:36
4	L4	97031	"TiO.sub.2" TiO2 "Ta.sub.2 O.sub.5" Ta2O5 "ZrO.sub.2" ZrO2 BaO BaO2 "BaO.sub.2" SrO SrO2 "SrO.sub.2"	USPAT; US-PGP UB; EPO; JPO; DERWEN T; IBM_TD B	2002/03/21 13:41
5	L5	29	1 and (2 or 4)	USPAT; US-PGP UB; EPO; JPO; DERWEN T; IBM_TD B	2002/03/21 13:42

09/617,254  
03/21/2002, EAST Version: 1.03.0002

2

	L #	Hits	Search Text	DBs	Time Stamp
6	L5	29	1 and (2 or 4)	USPAT; US-PGP UB; EPO; JPO; DERWEN T; IBM_TD B	2002/03/21 13:45
7	L7	2040	(427/553-559).CCLS.	USPAT; US-PGP UB; EPO; JPO; DERWEN T; IBM_TD B	2002/03/21 13:45
8	L8	232	7 and (2 or 4)	USPAT; US-PGP UB; EPO; JPO; DERWEN T; IBM_TD B	2002/03/21 13:46
9	L9	141	8 and (UV or ultraviolet or ultra violet)	USPAT; US-PGP UB; EPO; JPO; DERWEN T; IBM_TD B	2002/03/21 13:47

L10 (→) Circum or Titania  
 L11 31 (1 and 10) not (5 or 6)  
 Stupid computer (or programmer) doesn't know  
 the difference between or and + a plus

LS

3

	Document ID	Issue Date	Title	Current OR	Inventor
1	US 200100543 88 A1	20011227 <del>X</del>	Single-substrate-film-forming method and single-substrate-heat-processing apparatus	118/725	Qian, Shao Shou
2	US 6333065 B1	20011225 Cd. 7/17/98 K	Process for the production of an organic electroluminescent device	427/66	Arai, Michio et al.
3	<div style="position: relative;"> <div style="position: absolute; top: -20px; left: 0;">           (AD) sub- polymer, oxides... (D) the ceramic mat... <math>ZrO_2</math> </div>           US 6300641 B1 5/16/97 P11 → 4/11/97  Fig 1 - 1a-b-c         </div>	20011009	Process for modifying surfaces of materials, and materials having surfaces modified thereby	250/492.2 1	Koh, Seok Keun et al.
4	US 6270860 B1	20010807 4/25/95	Method of making push button switch covering with protective coating	427/536	Nakata, Toshihiro et al.

	Document ID	Issue Date	Title	Current OR	Inventor
5	US 6156114 A	20001205	Treatment of deagglomerated particles with plasma-activated species	106/400	Bell, Timothy Allan et al.
6	US 6103315 A	20000815 4/13/98	Method for modifying the surface of a thermal barrier coating by plasma-heating	427/454	Gray, Dennis Michael et al.

Full data

Ab5 - plasma spray

the plasma heat → removed

	Document ID	Issue Date	Title	Current OR	Inventor
7	US 6086726 A	20000711 5/19/98	Method of modifying a surface	204/192.1	Renk, Timothy J. et al.
<i>100 per</i>					
<i>Col. 8, l 26-31</i> <i>(B) the anti reflect coating ...</i> <i>... TiO<sub>2</sub>, ZnO<sub>2</sub>, H<sub>2</sub>O<sub>5</sub></i>	US 6051310 A	20000418 905 P. 1/1/96	Ophthalmic lens made of organic glass with a shockproof intermediate layer, and method for making same	428/336	Cano, Jean Paul et al.
<i>Col. 8, l 59-60</i> <i>may prefer anti Ref. Layer</i>	8				

full - cite only  
oxidizes to metal with  
containing ZrO<sub>2</sub>

(B) It has, for ex... 7/10/97  
containing ZrO<sub>2</sub>  
PCT Pub 4/1/96

	Document ID	Issue Date	Title	Current OR	Inventor
9	US 6033493 A	20000307 PCT Pub 4/1/96	Process for coating a passivated metal or alloy substrate with an oxide layer, and fuel assembly cladding and guide tubes and spacer grid coated with an oxide layer	148/276	Hertz, Dominique et al.
10	US 5972436 A X	19991026 7/24/97	CVD process for coating the inside of hollow bodies	427/535	Walther, Marten
11	US 5958524 A cont →	19990928 4/17/95	Process for the surface treatment of articles comprising at least one plastic material	427/533	Dehennau, Claude et al.
12	US 5945175 A DIV → 51814, 567	19990831 4/1/96	Durable hydrophilic coating for a porous hydrophobic polymer substrate	427/534	Yahiaoui, Ali et al.

(D) A. Calandrelli  
??  
11pdr of TiO<sub>2</sub>  
✓  
cont →

	Document ID	Issue Date	Title	Current OR	Inventor
13	US 5919326 A <i>DN-578157 5/1/95</i>	19990706	Method for the production of a fuel hose	156/244.13	Yokoe, Katsuhiko et al.
14	US 5853819 A	19981229	Imaging element comprising an electrically conductive layer formed by a glow discharge process	427/537	Lelental, Mark et al.
15	US 5780118 A <i>Coat on paper w/ TiO<sub>2</sub> filler</i>	19980714 <i>7/1/96</i>	Method for increasing hydrophilicity of transparencies used as recording media in a thermal ink jet printer	427/508	Tracy, Mark D. et al.
16	US 5780115 A <i>(B) In porous dielectric (B) Hydrothermal synthesis T=200-500°C; P=1-50k</i>	19980714 <i>2/2/97</i>	Methods for fabricating electrode structures including oxygen and nitrogen plasma treatments	427/539	Park, In-sung et al.
17	US 5718957 A	19980217	Fuel hose	428/36.91	Yokoe, Katsuhiko et al.

	Document ID	Issue Date	Title	Current OR	Inventor
18	US 5618388 A <i>dup Ta /ox dig/ dup Si/</i>	✓ 19970408	Geometries and configurations for magnetron sputtering apparatus	204/192.12	Seeser, James W. et al.
19	US 5562952 A	19961008	Plasma-CVD method and apparatus	427/534	Nakahigashi, Takahiro et al.
20	Abs ITO - $O^{+}$ <i>cheren deposit</i> US 5538905 A <i>Fig 3D <math>\downarrow O_2</math></i>	19960723	Method for forming a transparent conductive ITO film	438/609	Nishioka, Yukiya et al.

*100% protection*  
 $Col 4, 246 \quad O \equiv 10^{16} - 10^{17} \text{ imp/cm}^2$



	Document ID	Issue Date	Title	Current OR	Inventor
21	US 5468326 A	19951121	Apparatus for polishing a diamond or carbon nitride film by reaction with oxygen transported to the film through a superionic conductor in contact with the film	156/345	Cuomo, Jerome J. et al.
22	US 5466424 A	19951114	Corona discharge surface treating method	422/186.05	Kusano, Yukihiro et al.
23	US 5397597 A	19950314	Optical recording medium and method of manufacturing the same	427/255.6	Soga, Mamoru et al.

cd. 4.1 28-36  
 air +  $\text{H}_2$ ,  $\text{O}_2$   
 0.2-16 - sub 3

(B) It is possible... inorganic oxide layer  $\Rightarrow \text{TiO}_2$

B = metal oxide film

Ex 1 opt. red layer (2)  $(\text{TeO}_2 + \text{Te})$  dep. sub (1)  
 then apply another sub (1) w/ UV-adsorption, then  
 O-plasma treat in UV stepper

Ex 5 } sub 11 /  $(\text{TeO}_2 / \text{Te}) / \text{SiO}_2$  the O-plasma treat  
 6 }  $\text{TiO}_2$

(Fig 3)

	Document ID	Issue Date	Title	Current OR	Inventor
24	US 5328524 A <i>plasma etching metal</i>	19940712	Process for the surface oxidation of a part composed of passivatable metal, and fuel assembly elements composed of metal alloy covered with a protective oxide layer	148/241	Hertz, Dominique
25	US 5295220 A <i>Ab... TiO<sub>2</sub> film via plasma CVD</i> <i>(D) Prod. of waveguide of TiO<sub>2</sub>...</i> <i>protect - C - plasma</i>	19940315	Process for the production of a thin film optical waveguide of TiO <sub>2</sub> sub.2	385/142	Heming, Martin et al.
26	US 5268208 A <i>(D) H<sub>2</sub> internal plasma metal oxide = TiO<sub>2</sub></i>	19931207	Plasma enhanced chemical vapor deposition of oxide film stack	427/576	Krisko, Annette J. et al.
27	US 4816292 A	19890328	Method of preparing hexagonal ferrite element	427/539	Machida, Hajime

*(D) this treatment can be pref... ZnO<sub>2</sub>... TiO<sub>2</sub>...*

	Document ID	Issue Date	Title	Current OR	Inventor
28	US 4128426 A	19781205	Process for subbing photograp hic hydrophob ic films	427/536	Ohta, Hideyasu et al.
29	JP 60110379 A	19850615	METHOD FOR COATING POLYPROPY LENE RESIN PARTS		YUUSAI, KATSUICHI